

ABSTRACT

INSPECTION SYSTEM, SEMICONDUCTOR MANUFACTURING APPARATUS, AND INSPECTION METHOD

An inspection system includes a table, a camera, a first movement mechanism,
5 a second movement mechanism, and a control unit. The control unit controls the
camera, the first movement mechanism, and the second movement mechanism such
that a plurality of first partial image data respectively indicating different parts of an
electronic component are generated. The control unit executes: first processing for
subjecting each of the plurality of first partial image data to correction performed with
10 consideration given to an inclination of the camera with respect to a first axis and
correction with consideration given to a difference between an angle formed by the
first axis and a second axis and a reference angle; second processing for generating
composite image data by compositing the plurality of first partial image data after
correction: and third processing for inspecting the electronic component based on the
15 composite image data.

(Fig 1)